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In re application of  
Han Chen, et al  
Application No. 10/797,143  
Filed: March 11, 2004  
For: SYSTEMS AND METHODS FOR  
DETERMINING CONCENTRATIONS OF  
EXPOSURE

: DECISION ON PETITION  
: TO MAKE SPECIAL  
: (ACCELERATED  
: EXAMINATION)

This is in response to the renewed petition filed on March 14, 2006 to make the above-identified application special on the basis of special examining procedure for certain new applications - accelerated examination as set forth in MPEP § 708.02 VII.

The requirements for granting special status under this section are: (A) a petition to make special accompanied by the fee set forth in 37 CFR 1.17(l); (B) all claims being directed to a single invention, or an election without traverse if the Office determines that all the claims are not directed to a single invention; (C) a statement that a pre-examination search was made listing the field of search; (D) one copy of each of the references deemed most closely related to the subject matter encompassed by the claims if said references are not already of record; and (E) a detailed discussion of how the claimed subject matter is patentable over the references in accordance with 37 CFR 1.111 (b) and (c).

Since all of the requirements for special status under MPEP § 708.02 VII have been met, the petition is **GRANTED**.

The examiner is directed (1) to make an interference search for possible interfering applications, (2) to promptly examine this application out of turn, and (3) if any interfering application is discovered, to examine such application simultaneously and state in the first official letter of such application that it is being taken out of turn because of a possible interference.

Petitioner is advised that this application will continue to be special, throughout its entire prosecution and pendency, including interference or appeal, if any, only if petitioner makes a prompt *bona fide* effort, in response to each Office action, to place the application in condition for allowance, even if it is necessary to conduct an interview with the examiner to accomplish this purpose.

**SUMMARY:** Petition to Make Special GRANTED.

  
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Steven N. Meyers  
Special Programs Examiner  
Technology Center 3600  
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SNM/dcg: 3/27/06